

Title (en)
Method of vacuum-laminating adhesive film

Title (de)
Verfahren zur Vakuumlaminierung eines Klebefilms

Title (fr)
Méthode de laminage à vide d'un film adhésif

Publication
EP 1009206 A3 20030115 (EN)

Application
EP 99308985 A 19991111

Priority
JP 34241398 A 19981202

Abstract (en)
[origin: EP1009206A2] Herein is disclosed a vacuum-laminating method of an adhesive film while adhesive bleeding is reduced, i.e., a method of vacuum laminating an adhesive film which comprises a supporting base film disposed on at least one surface of a pattern-processed circuit substrate and a resin composition having a thermal flowability and being in the solid state at normal temperature disposed on the surface of said supporting base film so that said resin composition is laminated under heating and pressing conditions, said method comprising the steps of: (1) sheeting said adhesive film having the same size as or a smaller size than that of said circuit substrate in a state wherein the surface of said resin composition in said adhesive film is allowed to provisionally partially adhere to one surface or both surfaces of said circuit substrate; and (2) disposing a protecting film having an area larger than that of said adhesive film on said adhesive film provisionally adhering to said circuit substrate so that the center of said protecting film is disposed at substantially the same position as that of the center of said adhesive film, followed by vacuum laminating under heating and pressing conditions. Furthermore is disclosed the method as set forth above, further comprising a post-treatment step in which said adhesive film is smoothed by heating and pressing using a pressing metal plate or a laminating metal roll which can be used even when a protecting film having an area larger than that of said adhesive film is disposed between said supporting base film and said pressing metal plate or laminating metal roll, wherein said adhesive film comprises said supporting base film and said resin composition having a thermal flowability and being in the solid state at normal temperature disposed on the surface of said supporting base film and is vacuum-laminated in the order of supporting base film/resin composition/circuit substrate. <IMAGE>

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